



Form PTO-1449 (Rev. 8-88)	Attorney Docket No. ILL02-023-DIV-US	Serial No. 10/670,585
INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)	Applicant: Chang Liu, et al.	
	Filing Date: September 25, 2003	Group: 2881

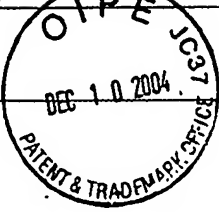
Examiner Initial*	OTHER ITEMS - NON PATENT LITERATURE DOCUMENTS	
	Include, as applicable: Author, Title, Date, Publisher, Edition or Volume, Pertinent Pages	
<i>9/2</i>	A1	Brittain, C., et al., "Soft Lithography and Microfabrication", 1998, Physics World, 11, 31-36.
<i>9/2</i>	A2	Kumar, A., et al., "Patterning Self Assembled Monolayers: Applications in Material Science", 1994, Langmuir, 10, pp. 1498-1511.
<i>9/2</i>	A3	Lopez, G.P., et al., "Fabrication and Imaging of Two-Dimensional Patterns of Proteins Adsorbed on Self-Assembled Monolayers by Scanning Electron Microscopy", 1993, Journal of American Chemical Society, 115, pp. 10774-10781.
<i>9/2</i>	A4	Branch, D.W., et al., "Microstamp Patterns of Biomolecules for High-Resolution Neuronal Networks", 1998, Medical and Biological Engineering and Computing, vol. 36, pp. 135-141.
<i>9/2</i>	A5	Marzolin, C., et al., "Patterning of a Polysiloxane Precursor to Silicate Glasses by Microcontact Printing", 1998, Thin Solid Films, 315, pp. 9-12.
<i>9/2</i>	A6	Xia, Y. et al., "Soft Lithography", 1998, Annual Review of Material Science, 28, pp. 153-84.
<i>9/2</i>	A7	K. Ryu, et al., "Precision Patterning of PDMS Thin Films: A New Fabrication Method and Its Applications", Sixth International Symposium on Micro Total Analysis System (mTAS), Nara, Japan, 3-7 November 2002
<i>9/2</i>	A8	Libiouille, L., et al., "Contact-Inking for Microcontact Printing of Alkanethiols on Gold", 1999, Langmuir, 15, pp. 300-304.
<i>9/2</i>	A9	Encyclopedia of Chemical Technology, Volume 14, Kirk-Othmer, 1995, pp. 677-709.
<i>9/2</i>	A10	Khoo, M., et al., "Micro Magnetic Silicone Elastomer Membrane Actuator", 2001, Sensors and Actuators, 89(3).
<i>9/2</i>	A11	Jo, B., et al., "Three-Dimensional Micro-Channel Fabrication in Polydimethylsiloxane (PDMS) Elastomer", 2000, J. MEMS, vol. 9, pp.76-81.
<i>9/2</i>	A12	Hertel, T., et al., "Manipulation of Individual Carbon Nanotubes and Their Interaction with Surfaces", 1998, Journal of Physical Chemistry B, Vol. 102, pp. 910-915.
<i>9/2</i>	A13	Snow, E., et al., "Nanofabrication with Proximal Probes", 1997, Proceedings of the IEEE, vol. 85, pp. 601-611.
<i>9/2</i>	A14	Wilson, D.L., et al., "Surface Organization and Nanopatterning of Collagen by Dip-Pen Nanolithography", 2001, PNAS, vol. 98, pp. 13660-13664.
<i>9/2</i>	A15	Belaubre, P., et al., "Fabrication of Biological Microarrays Using Microcantilevers", 2003, Applied Physics Letters, vol. 82, pp. 3122-3124.
<i>9/2</i>	A16	Lutwyche, M., et al., "5x5 2D AFM Cantilever Arrays A First Step Towards A Terabit Storage Device", 1999, Sensors and Actuators A: Physical, vol. 73, pp. 89-94.
<i>9/2</i>	A17	Vettiger, P., et al., "Ultrahigh Density, High-data-rate NEMS-based AFM Storage System", 1999, Microelectronic Engineering, vol. 46, pp. 101-104.
<i>9/2</i>	A18	Cooper, E.B., et al., "Terabit-Per-Square-Inch Data Storage With the Atomic Force Microscope", 1999, Applied Physics Letters, vol. 75, pp. 3566-3568.
<i>9/2</i>	A19	Piner, R.D., et al., "'Dip-Pen' Nanolithography", 1999, Science, vol. 283, pp. 661-663.

Examiner <i>James J. Thompson</i>	Date Considered <i>5/20/05</i>
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

992	A20	Wu, G., et al., "Origin of Nanomechanical Cantilever Motion Generated from Biomolecular Interactions", 2001, Proceedings of the National Academy of Sciences, vol. 98, pp. 1560-1564.
992	A21	Zhang, M., et al., "A MEMS Nanoplotter with High-Density Parallel Dip-Pen Nanolithography Probe Arrays", 2002, Journal of Nanotechnology, vol. 13, pp. 212-217.
992	A22	Chow, E.M., et al., "Characterization of a Two-Dimensional Cantilever Array with Through-Wafer Electrical Interconnects", 2002, Applied Physics Letters, vol. 80, pp. 664-666.
992	A23	Bullen, D., et al., "Micromachined Arrayed Dip Pen Nanolithography (DPN) Probes for Sub-100 nm Direct Chemistry Patterning", presented at 16 th International Conference on Micro Electro Mechanical Systems (MEMS), Kyoto, Japan, 2003.
992	A24	Minne, S.C., et al., "Parallel Atomic Force Microscopy Using Cantilevers with Integrated Piezoresistive Sensors and Integrated Piezoelectric Actuators", 1995, Applied Physics Letters, vol. 67, pp. 391803920.
992	A25	Liu, C., et al., "Mass-Producible Monolithic Silicon Probes for Scanning Probe Microscopes", 1998, Sensors and Actuators A: Physical, vol. 71, pp.
992	A26	Petersen, K.E., "Silicon As A Mechanical Material" 1982, Proceedings of the IEEE, vol. 70, pp. 420-457.
992	A27	Minne, S.C., et al., "Centimeter Scale Atomic Force Microscope Imaging and Lithography", 1998, Applied Physics Letters, vol., 73, pp. 1742-1744.
992	A28	Bullen, D., et al., "Thermo-Mechanical Optimization of Thermally Actuated Cantilever Beam Array" July 2002, Proc. SPIE Vol. 4700, Smart Structures and Materials 2002: Smart Electronics, MEMS, and Nanotechnology, pp. 288-295; with separate abstract.
992	A29	Wang, X., et al., "Scanning Probe with Elastomeric (PDMS) Tip for Scanning Probe Microcontact Printing (SP-uCP)", presented at the 12 th International Conference on Solid-State Sensors, Actuators and Microsystems, Boston, MA, June 8-12, 2003.
992	A30	Wang, X., et al., "Scanning Probe Contact Printing", 2003, Langmuir, Vol. 19, pp. 8951-8955.

James P. Heyl 5/20/05

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U.S. PATENT DOCUMENTS							
Examiner Initials*		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
<i>JPZ</i>	B1	5,883,387	03/1999				
<i>JPZ</i>	B2	6,156,215	12/2000				

FOREIGN PATENT DOCUMENTS								
Examiner Initials*		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
<i>JPZ</i>	B3	EP 0786642	07/1997	EP				
<i>JPZ</i>	B4	WO99/56176	11/1999	WO				

Examiner Initials*		OTHER ITEMS - NON PATENT LITERATURE DOCUMENTS	
		Include, as applicable: Author, Title, Date, Publisher, Edition or Volume, Pertinent Pages	
<i>JPZ</i>	B5	Higa, K. et al., "Fabrication of Microcantilever with a Silicon Tip Prepared by Anodization", Japanese Journal of Applied Physics, vol. 37, no. 12B, pp. 7078-7080, (1998).	
<i>JPZ</i>	B6	International Search Report for application no. PCT/US2004/015161 dated October 27, 2004.	

Examiner <i>James J. Lyfman</i>	Date Considered <i>5/20/05</i>
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